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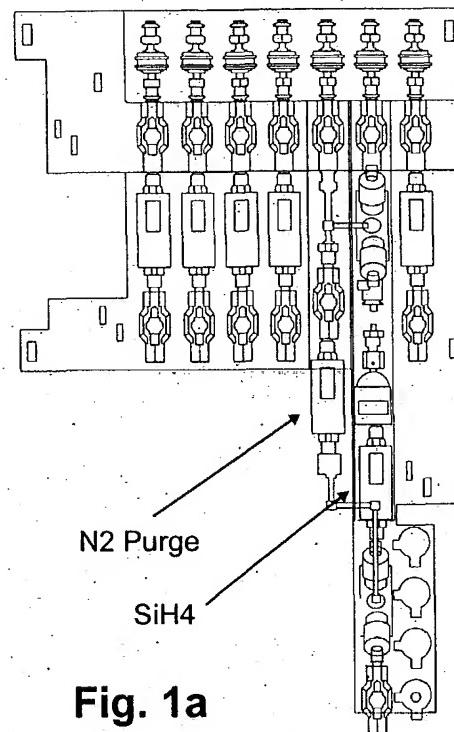


Fig. 1a

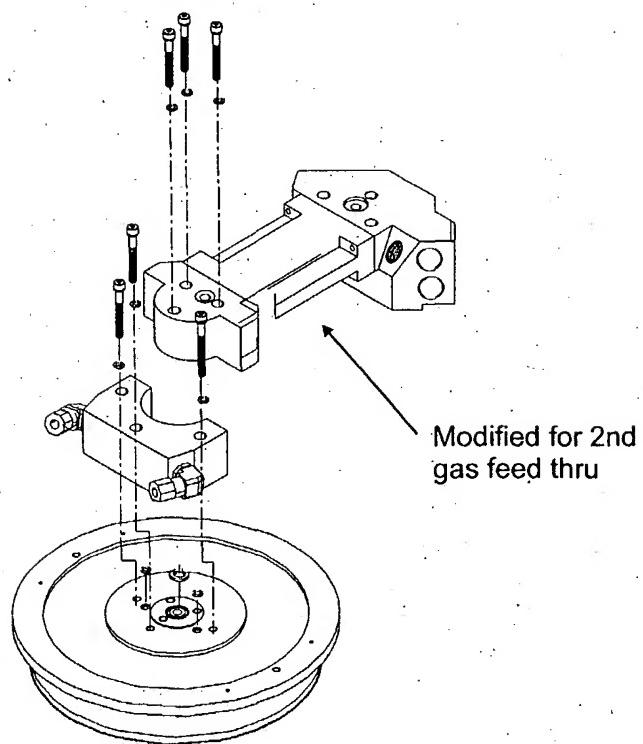


Fig. 1b

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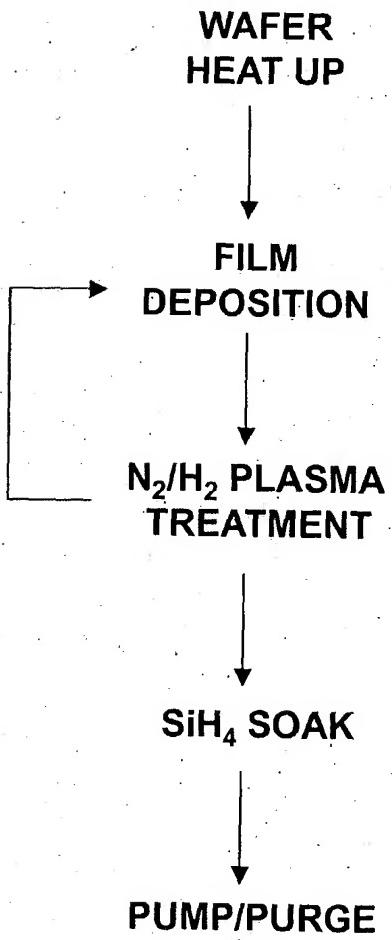


Fig. 2

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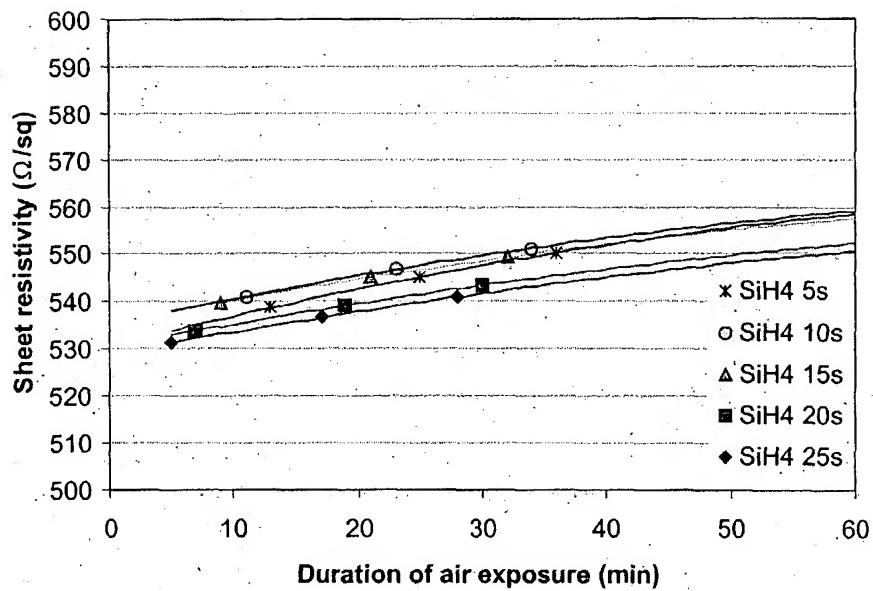


Fig. 3A

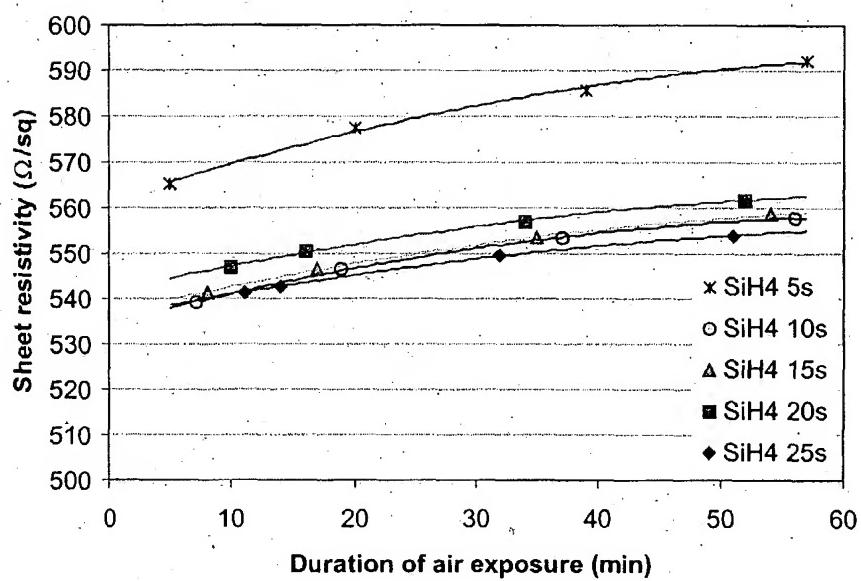


Fig. 3B

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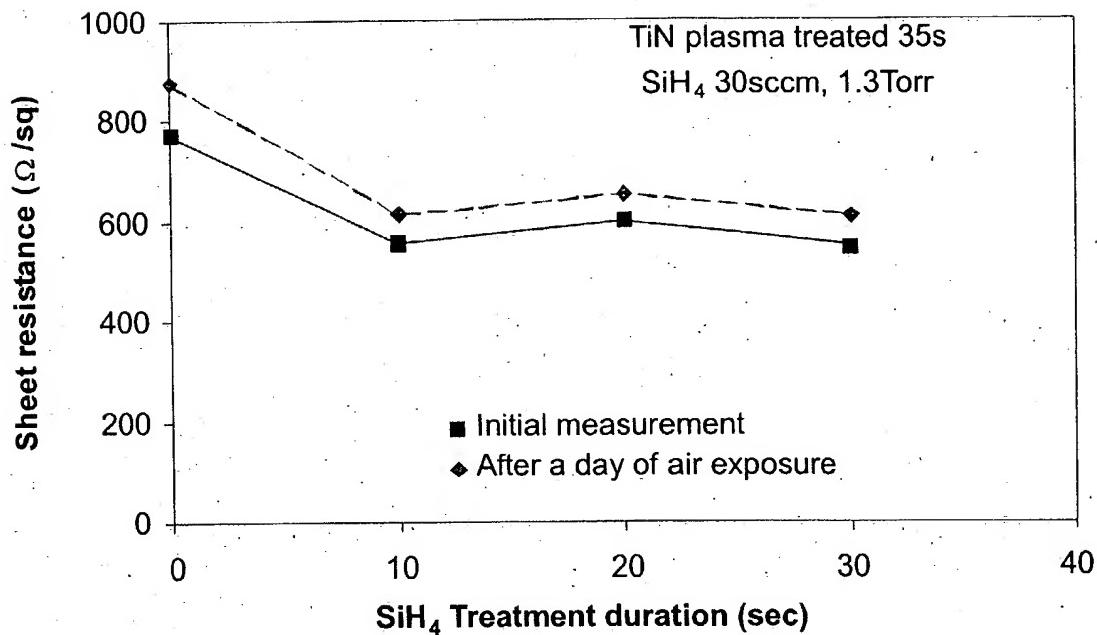


Fig. 4A

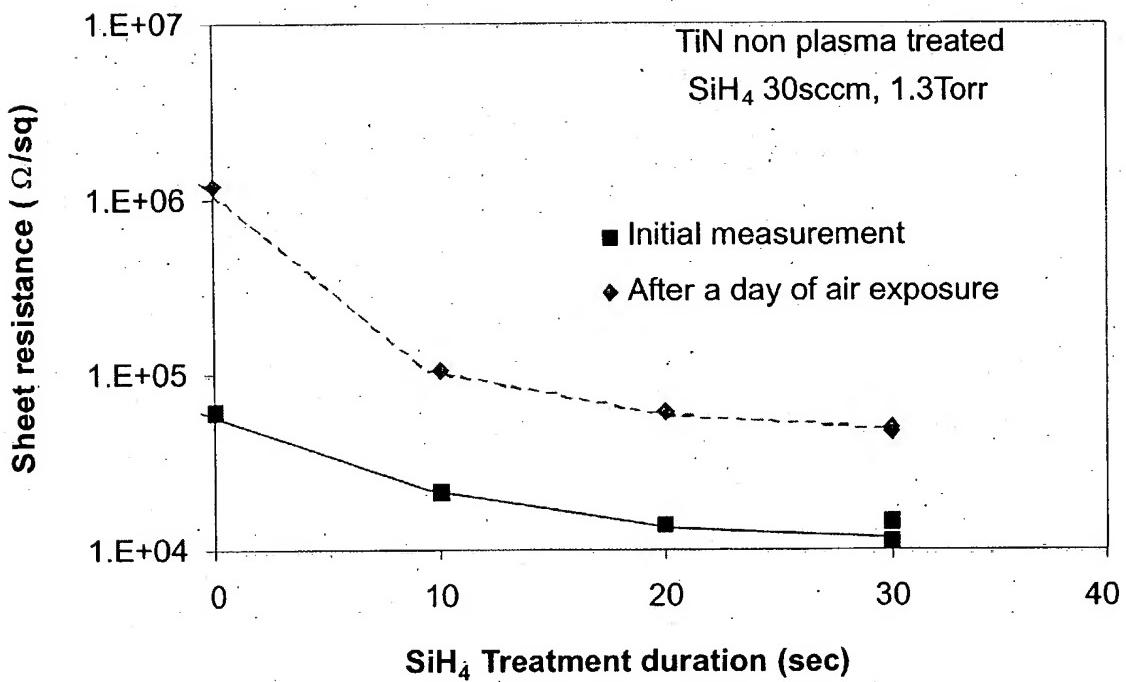


Fig. 4B

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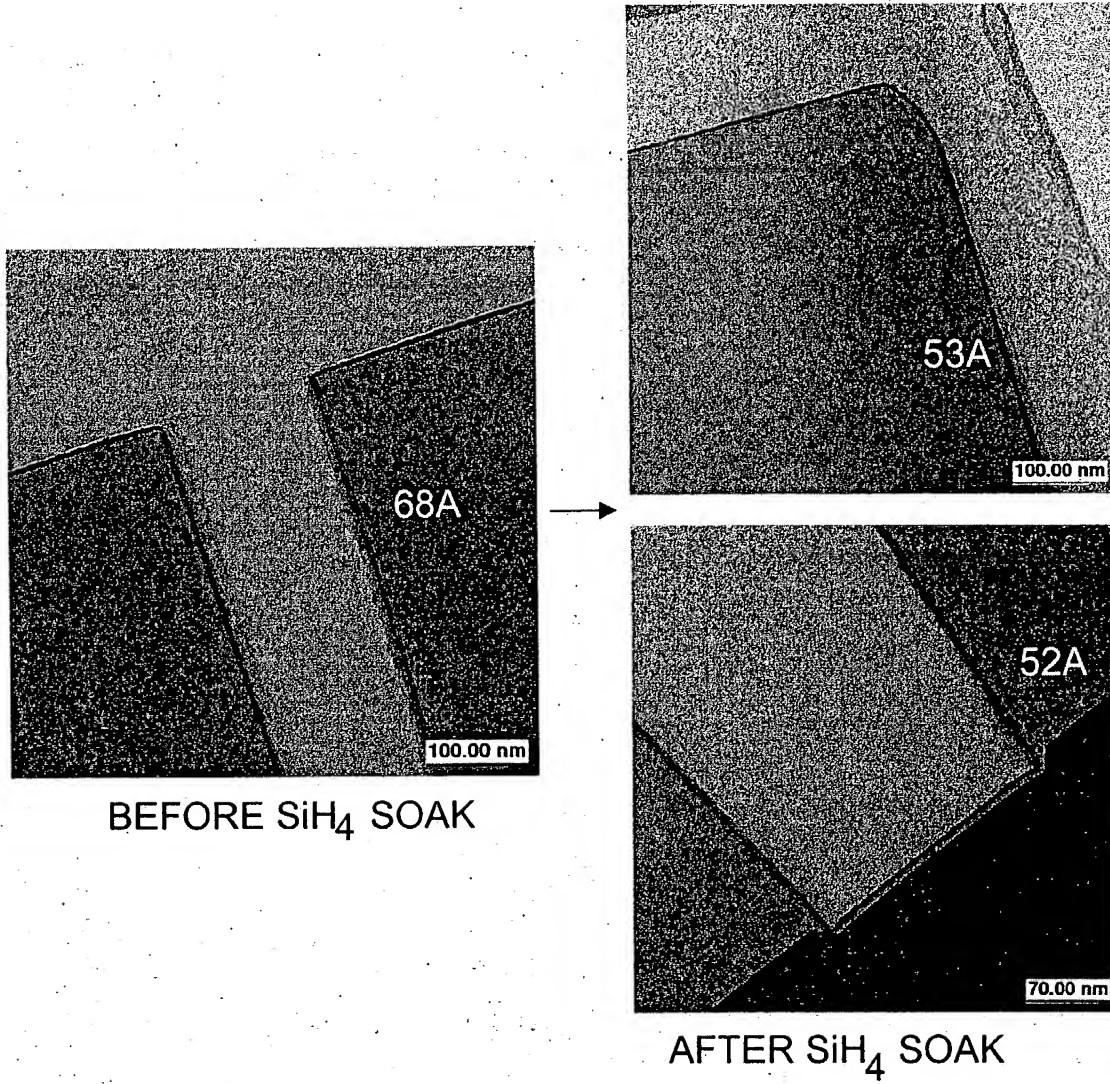


Fig. 5.

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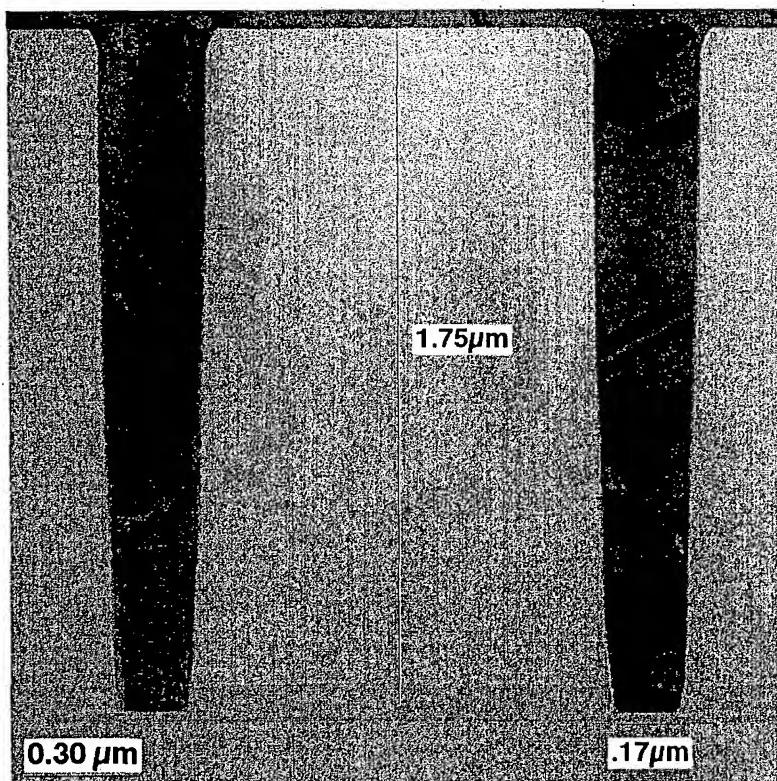
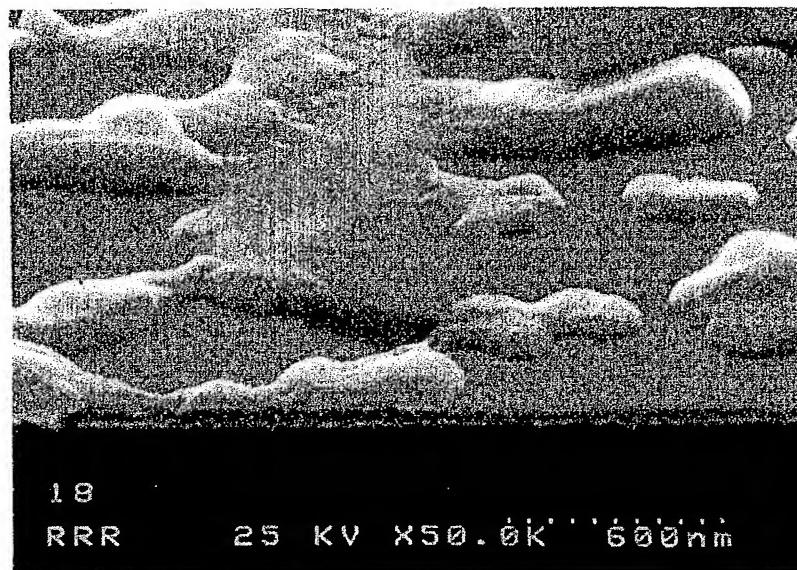


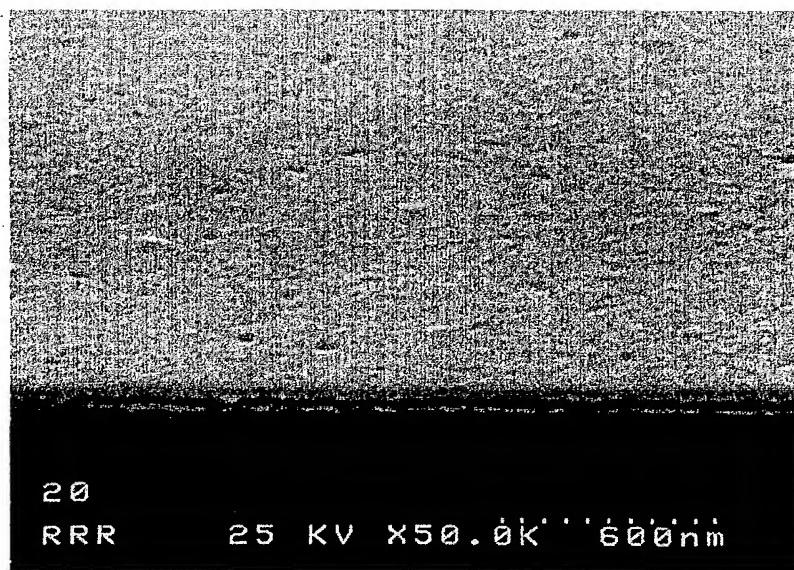
Fig. 6

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1x50 TiN Plasma

Fig. 7A



1x50 TiSiN Plasma

Fig. 7B

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80 sccm SiH₄, 300 sccm N₂, 2.0 Torr

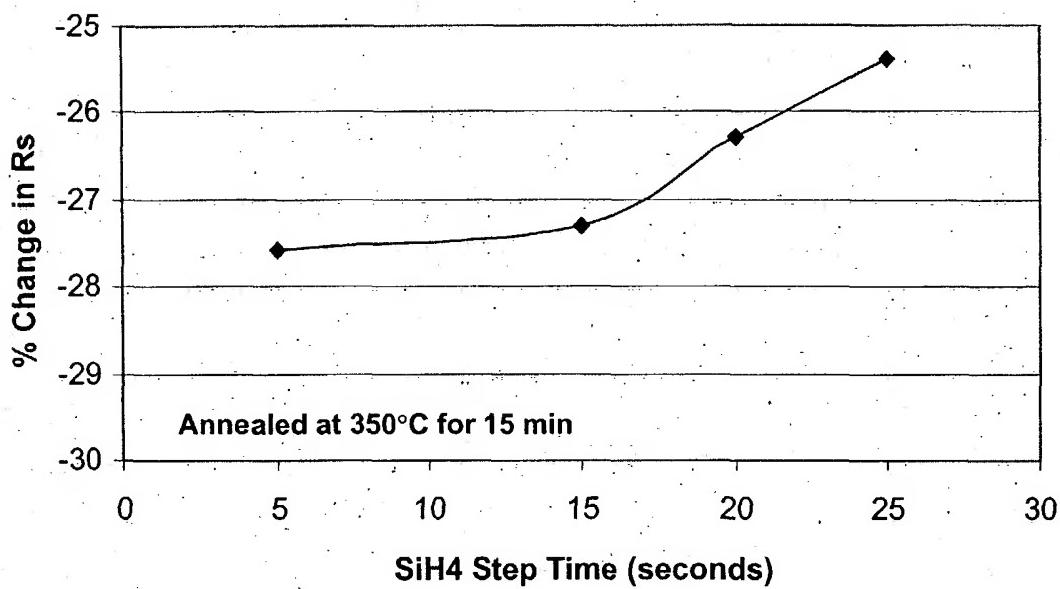


Fig. 8

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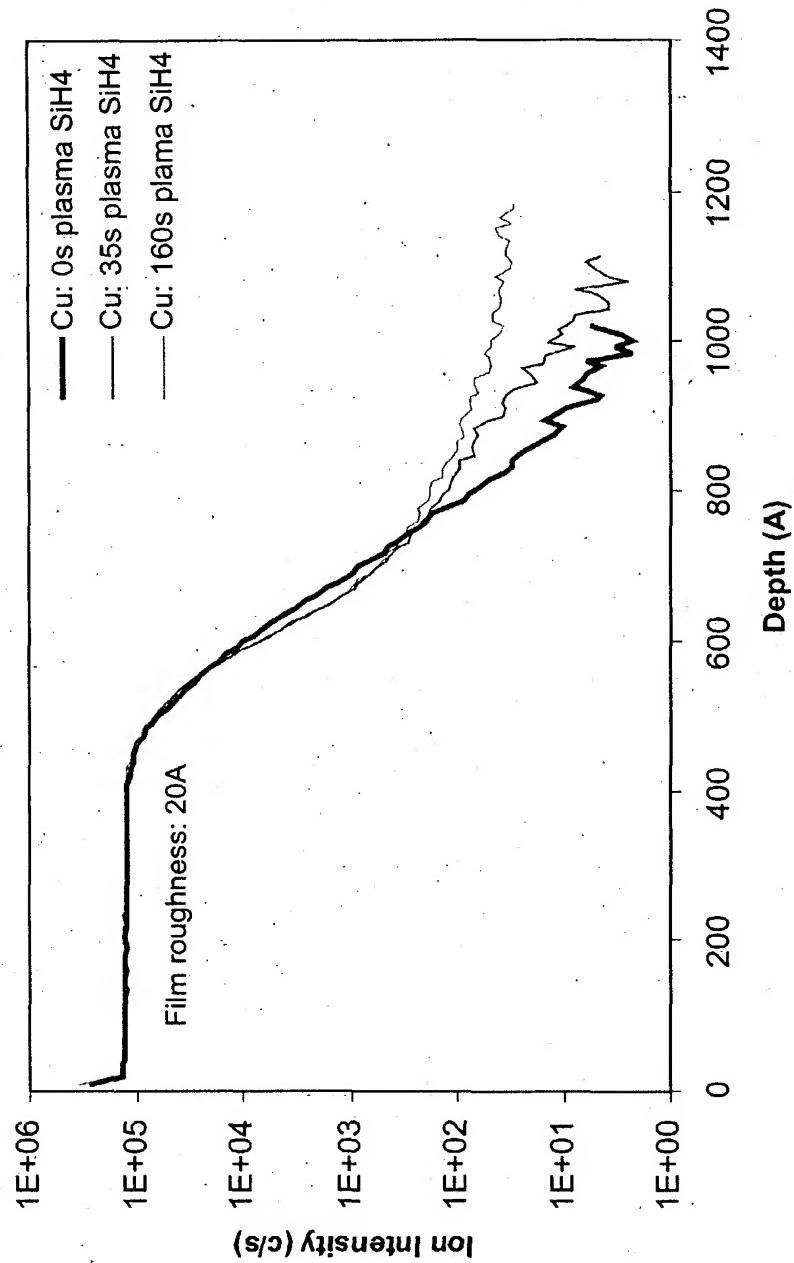


Fig. 9

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1x50 TiSiN Sheet Resistance and Rs Uniformity

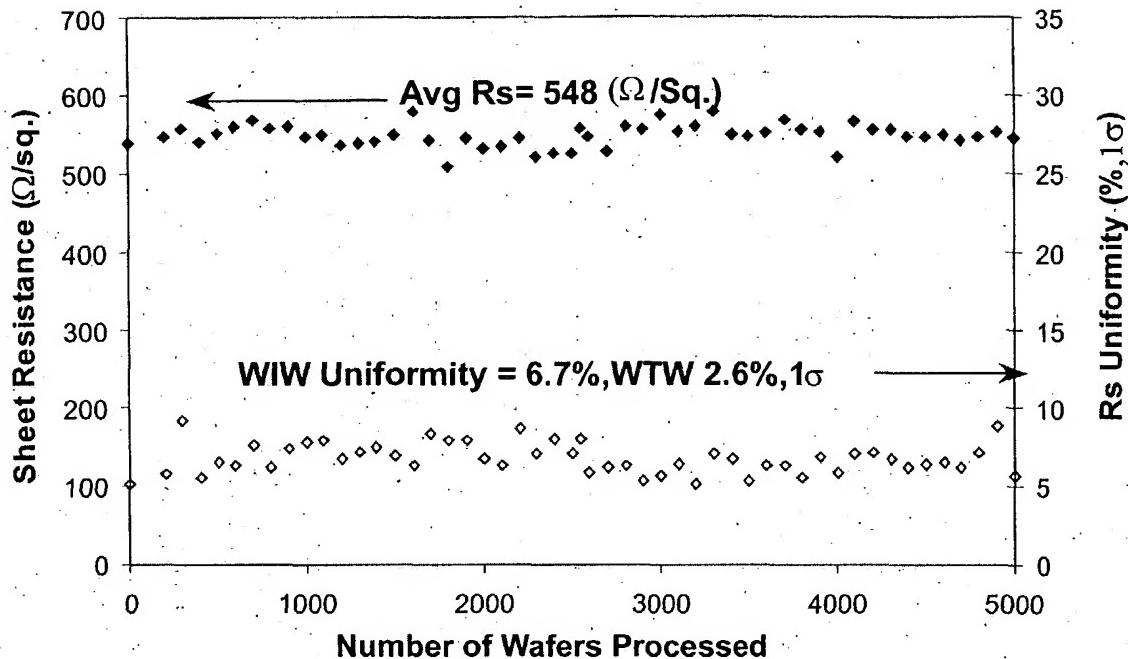


Fig. 10A

1X35 TiSiN Rs and Rs Uniformity

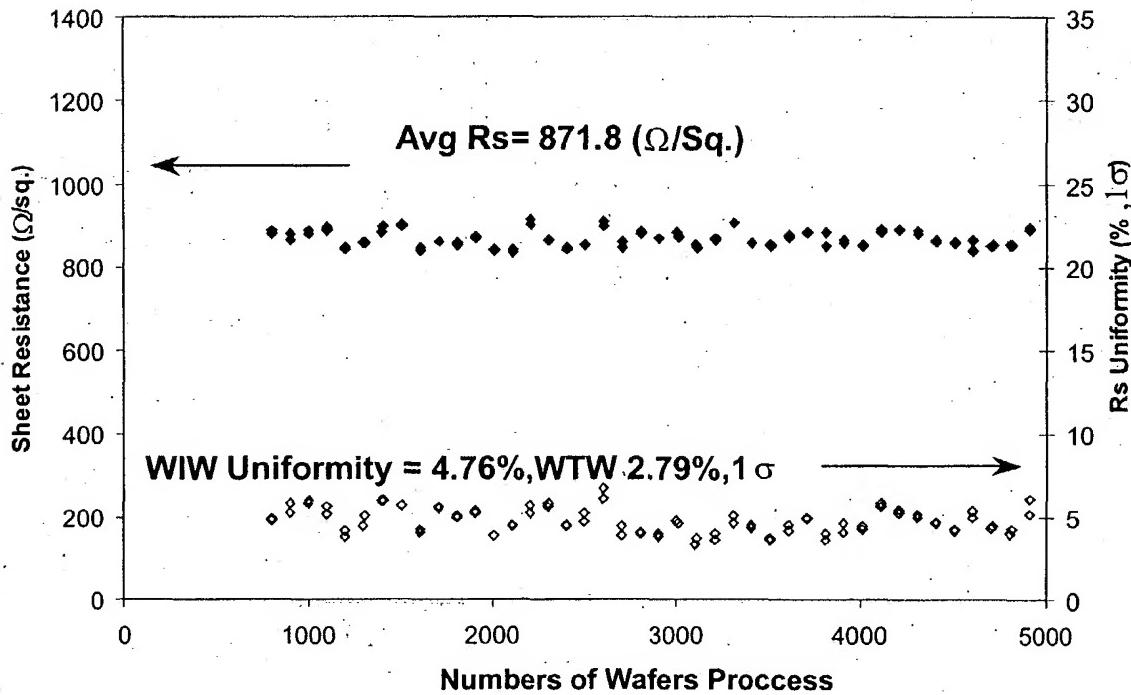


Fig. 10B

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1x50 TiSiN Thickness Reproducibility

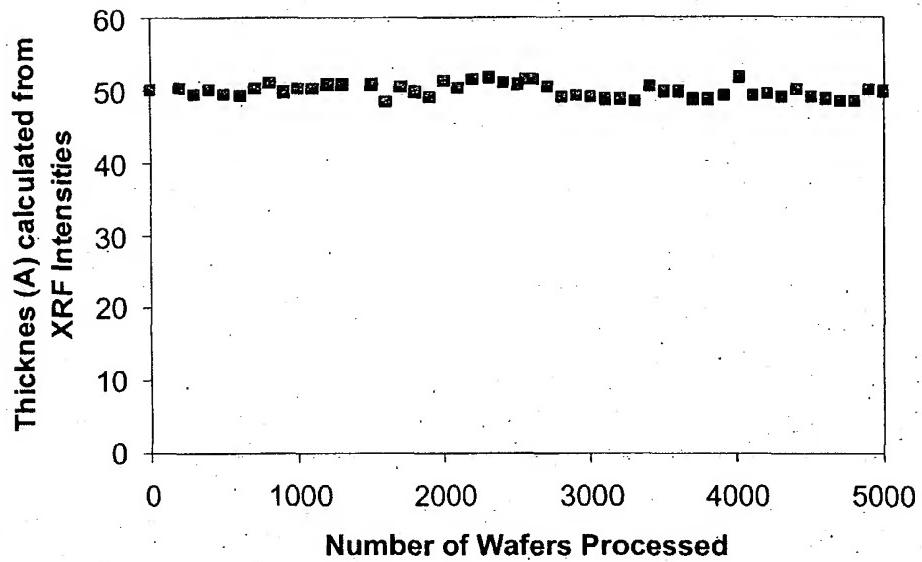


Fig. 11A

1x35 TiSiN Thickness Reproducibility

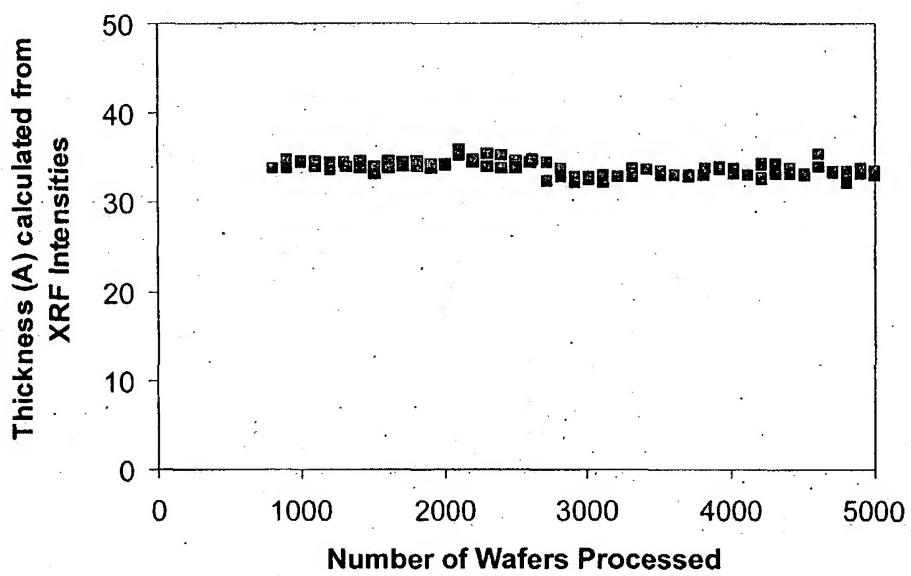


Fig. 11B

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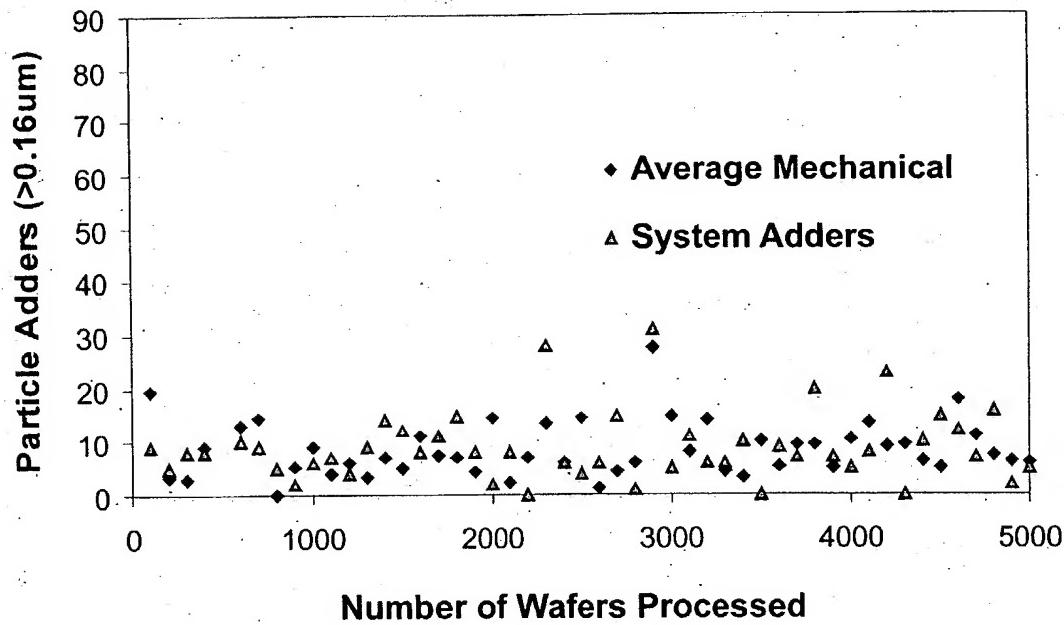


Fig. 12A

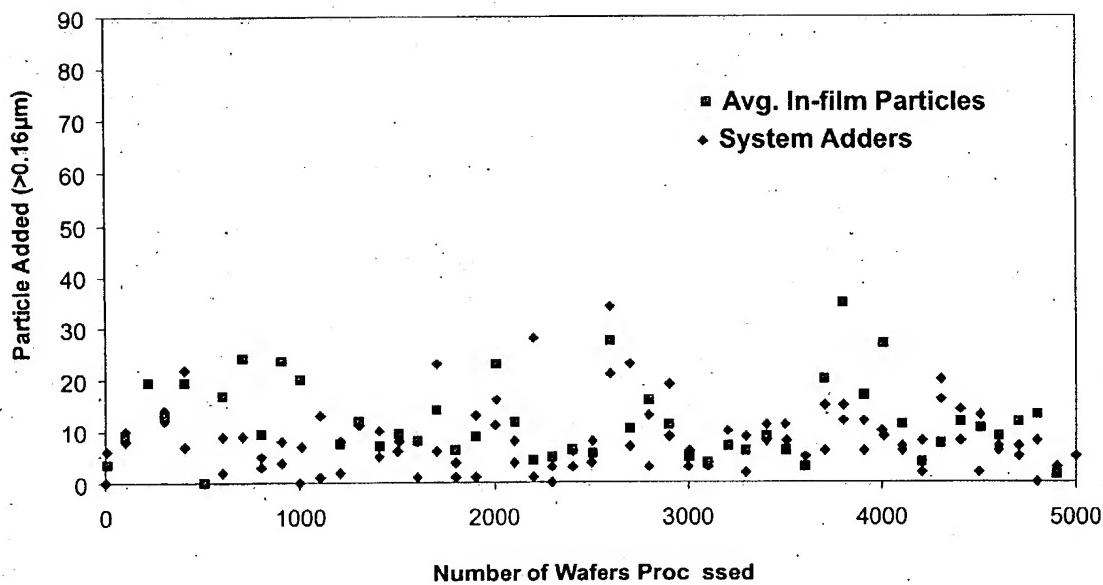


Fig. 12B

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1x50 TiSiN Rs and Rs Uniformity After 1 Hour Idle

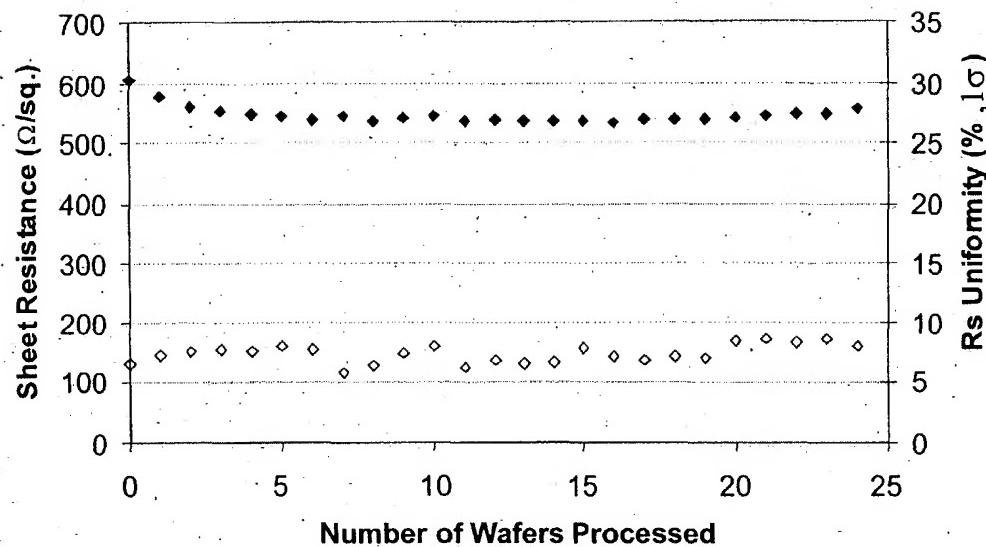


Fig. 13A

1X50 TiSiN Thickness from XRF Intensities After 1 Hour Idle

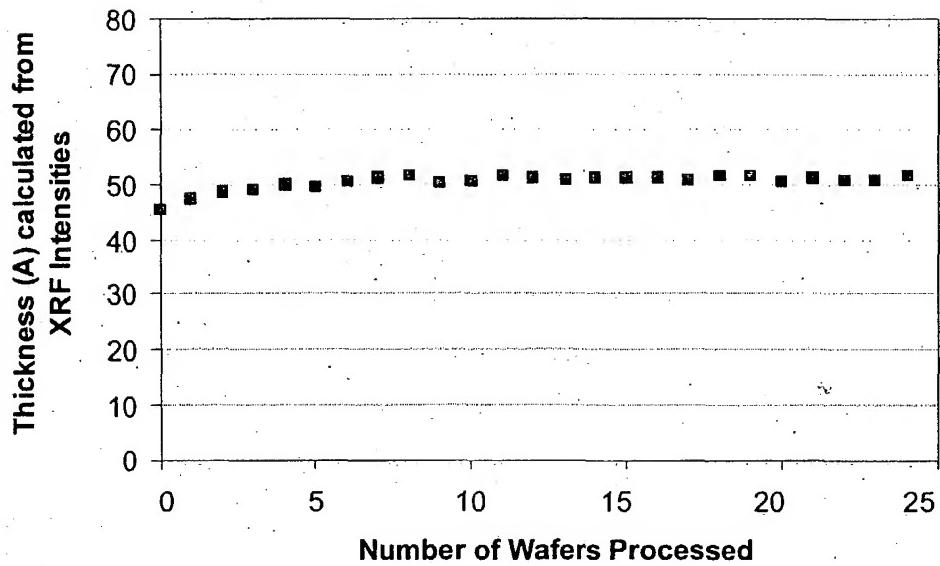


Fig. 13B